



Attorney Docket: 622/48561
PATENT

#24/C
12.29.21

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: MARTIN DUBS ET AL.
Serial No.: 09/484,421 Group Art Unit: 1753
Filed: JANUARY 18, 2000 Examiner: G. CANTELMO
Title: SPUTTER CHAMBER AS WELL AS VACUUM TRANSPORT
CHAMBER AND VACUUM HANDLING APPARATUS WITH
SUCH CHAMBERS

AFTER-FINAL REPLY UNDER 37 CFR §1.116
EXPEDITED HANDLING REQUESTED

Commissioner for Patents
Washington, D.C. 20231

Sir:

The following is responsive to the Office Action mailed on or about April
18, 2002. A Notice of Appeal was filed September 18, 2002.

RECEIVED
DEC 23 2002
TC 1700

IN THE DRAWINGS:

A Letter Requesting Drawing Change Approval is submitted herewith.

IN THE CLAIMS:

(A marked-up version of the amended claims is attached to this
Amendment.)

Please amend Claims 35, 47, 48, 50 and 58 as follows:

35. (Amended) Sputtering chamber comprising at least one sputtering
source with a new sputter surface at least approximately symmetrical with

DI